



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tadahiro OHMI et al.
Title: VACUUM PROCESSING APPARATUS AND VAPOR
DEPOSITION APPARATUS
Appl. No.: 10/568,706
International Filing Date: 8/19/2004
371(c) Date: 4/28/2006
Examiner: Keath T. Chen
Art Unit: 1792
Confirmation Number: 4847

AMENDMENT AND REPLY UNDER 37 CFR 1.116

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Final Office Action dated September 29, 2009, concerning the above-referenced patent application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this document.

Remarks/Arguments begin on page 4 of this document.

Please amend the application as follows: